PH

## CLAIMS

What is claimed is:

- 1. A system for measuring a phase difference between light signals reflected from both sides of a first object comprising:
  - a first miniature optic system having
- a first light source for transmitting a first light signal toward a first surface of said first object, said first light signal reflecting off said first surface having a first and second reflected polarized light signal components;
  - a first polarization splitter for separating the first reflected polarized light signal component and the second reflected polarized light signal component from said reflected first light signal;
  - a first detector for detecting a first intensity of said first reflected polarized light signal component;
  - a second detector for detecting a second intensity of said second reflected polarized light signal component; and
  - a first phase determinator for determining a first difference in phase between said first and second reflected polarized light signal components based upon said first and second intensities; and
  - a second miniature optic system having:

a second light source for transmitting a second light signal toward a second surface of said first object, said second light signal reflecting off said second surface having a third and fourth reflected polarized light signal components;

a second polarization splitter for separating the third reflected polarized light signal component and the fourth reflected polarized light signal component from said reflected second light signal;

a third detector for detecting a third intensity of said third reflected polarized light signal component;

a fourth detector for detecting a fourth intensity of said fourth reflected polarized light signal component; and

a second phase determinator for determining a second difference in phase between said third and fourth reflected polarized light signal components based upon said third and fourth intensities.

- 2. The system of claim 1, wherein said first object is one of a magnetic disk and a silicon wafer.
- 3. The system of claim 2, wherein said first and second phase determinators comprise:

a texture eliminator for determining a difference between said first and second intensities to reduce the effects of a texture on said first object.

- 4. The system of claim 1, wherein said first miniature optic system further comprises:
- a first thickness determinator for determining a thickness of a lubricant on said first surface based upon said first difference in phase.
- 5. The system of claim 4, wherein said second miniature optic system further comprises:
- a second thickness determinator for determining a thickness of a lubricant on said second surface based upon said second difference in phase.
- 6. The system of claim 1, wherein said first miniature optic system further comprises:
- a first carbon thickness determinator for determining a thickness of a carbon layer of said first surface based upon said first difference in phase.
- 7. The system of claim 6, wherein said second miniature optic system further comprises:

a second carbon thickness determinator for determining a thickness of a carbon layer of said second surface based upon said second difference in phase.

- 8. The system of claim 1, wherein said first miniature optic system further comprises:
- a first magnetic identifier for determining a magnetic characteristic of said first surface based upon said first difference in phase.
- 9. The system of claim 8, wherein said second miniature optic system further comprises:
- a second magnetic identifier for determining a magnetic characteristic of said second surface based upon said second difference in phase.
- 10. The system of claim 1, wherein said first miniature optic system further comprises:
- a first Kerr effect determinator for measuring the magnetooptic Kerr effect of said first surface based upon said first difference in phase.
- 11. The system of claim 10, wherein said second miniature optic system further comprises:

a second Kerr effect determinator for measuring the magneto-optic Kerr effect of said second surface based upon said second difference in phase.

- 12. The system of claim 10, wherein said first miniature optic system further comprises:
- a first defect determinator for determining whether a first defect exists at a first location on the first surface based upon said first and second intensities.
- 13. The system of claim 12, wherein said second miniature optic system further comprises:
- a second defect determinator for determining whether a second defect exists at a first location on the second surface based upon said third and fourth intensities.
  - 14. The system of claim 13, further comprising:
- a first mechanical scribe for marking said first location to identify said first defect.
  - 15. The system of claim 14, further comprising:
- a second mechanical scribe for marking said second location to identify said second defect.

16. The system of claim 14, further comprising:

a scribe positioner for moving said first mechanical scribe to a position substantially adjacent to said first location before marking said first location.

- 17. The system of claim 1, wherein said first miniature optic system further comprises:
- a first defect determinator for determining whether a first defect exists at a first location on the first surface based upon said first and second intensities.
- 18. The system of claim 17, wherein said second miniature optic system further comprises:
- a second defect determinator for determining whether a second defect exists at a first location on the second surface based upon said third and fourth intensities.
  - 19. The system of claim 18, further comprising:
- a first mechanical scribe for marking said first location to identify said first defect.
  - 20. The system of claim 19, further comprising:
- a second mechanical scribe for marking said second location to identify said second defect.

- 21. The system of claim 19, further comprising:

  a scribe positioner for moving said first mechanical scribe to a position substantially adjacent to said first location before marking said first location.
- 22. The system of claim 1, wherein said first reflected polarized light signal component and said second reflected polarized light signal are orthogonally polarized.
- 23. The system of claim 1, wherein said first reflected polarized light signal component and said second reflected polarized light signal are non-orthogonally polarized.
- 24. The system of claim 1, wherein said third reflected polarized light signal component and said fourth reflected polarized light signal are orthogonally polarized.
- 25. The system of claim 1, wherein said third reflected polarized light signal component and said fourth reflected polarized light signal are non-orthogonally polarized.